Ref #	Hits	Search Query	DBs	Default Operator	Piurais	Time Stamp
2	457	"445"/\$.ccls. and ((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure atmosphere))	US-PGPUB; USPAT	OR	N O	2005/10/15 19:13
ៗ	239	"445"/24-25.ccls. and ((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure atmosphere))	US-PGPUB; USPAT	OR	NO	2005/10/15 16:45
47	100	"445"/24-25.ccls. and ((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure atmosphere)) and ((plural plurality multiple different) with (enclosure furnace chamber stage station))	US-PGPUB; USPAT	S S	NO	2005/10/15 16:46
2	125	"445"/24-25.ccls. and ((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure atmosphere)) and ((plural plurality several multiple different individual separate) with (enclosure furnace chamber stage station))	US-PGPUB; USPAT	S S	NO	2005/10/15 16:47
97	224	"445"/\$.ccls. and ((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station) and ((enclosure furnace chamber stage station) with (pressure atmosphere) and ((plural plurality several multiple different individual separate) with (enclosure furnace chamber stage station))	US-PGPUB; USPAT	SO.	NO	2005/10/15 16:54
77	200	"445"/\$.ccls. and ((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure atmosphere)) and ((plural plurality several multiple different individual separate) with (enclosure furnace chamber stage station)) and (firing fired bak\$3 calcinat\$3 heat\$3) and (seal\$3 attach\$3 bond\$3 bind\$3)	US-PGPUB; USPAT	OR	NO	2005/10/15 17:43
87 	П	"6905384".pn.	US-PGPUB; USPAT	OR	N O	2005/10/15 17:27
61	17	("20020039870" "4607593" "5066883" "5433639" "5564958" "5605483" "5653838" "5697825" "5749763" "5827102" "5876260" "6004181" "6049168" "6254449" "6479944" "6702636" "6821174").PN. OR ("6905384").URPN.	US-PGPUB; USPAT; USOCR	OR	NO	2005/10/15 17:27
L10		"445"/\$.ccls. and ((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure vacuum atmosphere) with (degree reduc\$4 increas\$3 lower\$3)) and (firing fired bak\$3 calcinat\$3 heat\$3) and (seal\$3 attach\$3 bond\$3 bind\$3)	US-PGPUB; USPAT	O _X	NO	2005/10/15 17:50

2005/10/15 17:51	2005/10/15 18:10	2005/10/15 17:52	2005/10/15 17:53	2005/10/15 17:58	2005/10/15 18:01	2005/10/15 18:01	2005/10/15 18:01	2005/10/15 18:11
NO	N O	NO	N O	N O	N O	N O	NO O	NO
NO N	SO.	8	R	R	OR S	OR S	S S	OR
US-PGPUB; USPAT	EPO; JPO; DERWENT	EPO; JPO; DERWENT	EPO; JPO; DERWENT	EPO; JPO; DERWENT	EPO; JPO; DERWENT	EPO; JPO; DERWENT	DERWENT	USPAT
"445"/\$.ccls. and ((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure vacuum atmosphere) with (degree reduc\$4 increas\$3 lower\$3)) and ((firing fired bak\$3 calcinat\$3 heat\$3) same (pressure vacuum atmosphere)) and ((seal\$3 attach\$3 bond\$3 bind\$3) same (pressure vacuum atmosphere)) and (clean\$3 same (pressure vacuum atmosphere))	((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure vacuum atmosphere) with (degree reduc\$4 increas\$3 lower\$3)) and ((firing fired bak\$3 calcinat\$3 heat\$3) same (pressure vacuum atmosphere)) and ((seal\$3 attach\$3 bond\$3 bind\$3) same (pressure vacuum atmosphere)) and (clean\$3 same (pressure vacuum atmosphere))	((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure vacuum atmosphere) with (degree reduc\$4 increas\$3 lower\$3))	((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure vacuum atmosphere) with (degree reduc\$4 increas\$3 lower\$3)) and (display device panel)	((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((enclosure furnace chamber stage station) with (pressure vacuum atmosphere) with (degree reduc\$4 increas\$3 lower\$3)) and ((image flat) near3 (display device panel))	"2000182524"	"2003059403"	2003-305707.NRAN.	((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((firing fired bak\$3 calcinat\$3 heat\$3) same (pressure vacuum atmosphere)) and ((seal\$3 attach\$3 bond\$3 bind\$3) same (pressure vacuum atmosphere)) and (clean\$3 same (pressure vacuum atmosphere)) and (clean\$3 same (pressure vacuum atmosphere)) and "445"/\$.ccls.
76	19	8742	2305	02	2	4	H	156
=	112	L13	114	115	L16	117	L18	L19

2005/10/15 18:11	2005/10/15 18:44	2005/10/15 18:45	2005/10/15 18:46	2005/10/15 19:06	2005/10/15 19:09	2005/10/15 19:07	2005/10/15 19:13	2005/10/15 19:14	2005/10/15 19:24	2005/10/15 19:27
NO .	No.	NO	NO	NO	NO	NO	NO	NO	NO	NO
RO RO	OR .	S S	S S	S S	OR	OR S	OR	OR S	S.	OR
US-PGPUB; USPAT	US-PGPUB; USPAT	US-PGPUB; USPAT	US-PGPUB; USPAT; USOCR	US-PGPUB; USPAT; USOCR	EPO; JPO; DERWENT	DERWENT	EPO; JPO; DERWENT	EPO; JPO; DERWENT	EPO; JPO; DERWENT	EPO; JPO; DERWENT
((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((firing fired bak\$3 calcinat\$3 heat\$3) same (pressure vacuum atmosphere)) and ((seal\$3 attach\$3 bond\$3 bind\$3) same (pressure vacuum atmosphere)) and ((clean\$3 getter\$3) same (pressure vacuum atmosphere)) and ((clean\$3 getter\$3) same (pressure vacuum atmosphere)) and "445"/\$.ccls.	((process\$3 manufact\$3 fabricat\$3) with (enclosure furnace chamber stage station)) and ((firing fired bak\$3 calcinat\$3 heat\$3) with (pressure vacuum atmosphere)) and ((seal\$3 attach\$3 bond\$3 bind\$3) with (pressure vacuum atmosphere)) and ((clean\$3 getter\$3) with (pressure vacuum atmosphere)) and ((clean\$2 getter\$3) with (pressure vacuum atmosphere)) and "445"/\$.ccls.	"6634916".pn.	("4904895" "5066883" "5591061" "5605483" "5749763" "5820435" "6049168" "6139390" "6254449" "6309272" "6419539").PN. OR ("6634916").URPN.	("4031552" "5529524" "5689151" "5697825" "5827102" "5936342" "5977706" "6008576" "6634916").PN. OR ("6926575").URPN.	"6926575"	2001-015679.NRAN.	"717429" "04289640" "05151916" "08022785" "08022785" "09082245" "09171768"	((process\$3 manufact\$3 operation\$3 fabricat\$3) with (vacuum pressure atmosphere) (enclosure furnace chamber stage station)) and ((flat image) near3 (display device panel apparatus))	((process\$3 manufact\$3 operation\$3 fabricat\$3) with (vacuum pressure atmosphere) with (similar "same" equal reduc\$4 lower\$3) with (enclosure furnace chamber stage station)) and ((flat image) near3 (display device panel apparatus))	((process\$3 manufact\$3 operation\$3 fabricat\$3) with (vacuum pressure atmosphere) with (constant uniform identical even equivalent) with (enclosure furnace chamber stage station)) and ((flat image) near3 (display device panel apparatus))
257	180	H	12	0	н	H	15	23630	23	10
720	2	122	173	124	125	176	777	827	67	L30

131	86	((process\$3 manufact\$3 operation\$3 fabricat\$3) with (vacuum pressure atmosphere) with (constant uniform identical even equivalent similar "same" equal increas\$3 decreas\$3 lower\$3 higher) with (enclosure furnace chamber stage station)) and ((flat image) near3 (display device panel apparatus)) and ("445"/\$.cds.)	US-PGPUB; OR	OR	NO	2005/10/15 19:29
132	12	12 ("3611077").PN. OR ("6017259").URPN.	US-PGPUB; OR USPAT; USOCR	S S	NO	2005/10/15 19:32